Ápplication No. 09/831,88, Reply to Office Action of August 11, 2003

IN THE SPECIFICATION

Please replace the paragraph beginning at page 25, line 7, with the following rewritten paragraph:

13/

The ceramic heater of the present invention can be provided with static electrodes required for use as an electrostatic chuck, or with a chuck top surface conductor layer required for use as a wafer prover prober.

Please replace the paragraph beginning at page 40, line 18, with the following rewritten paragraph:



This heater can be applied to an electrostatic chuck and a wafer prover prober.